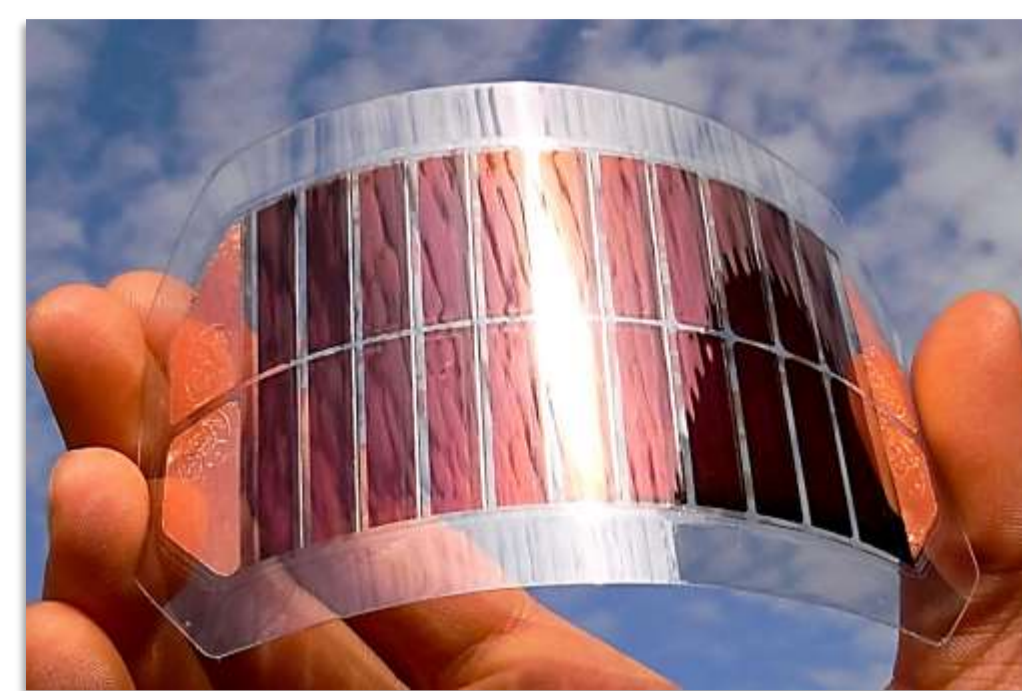




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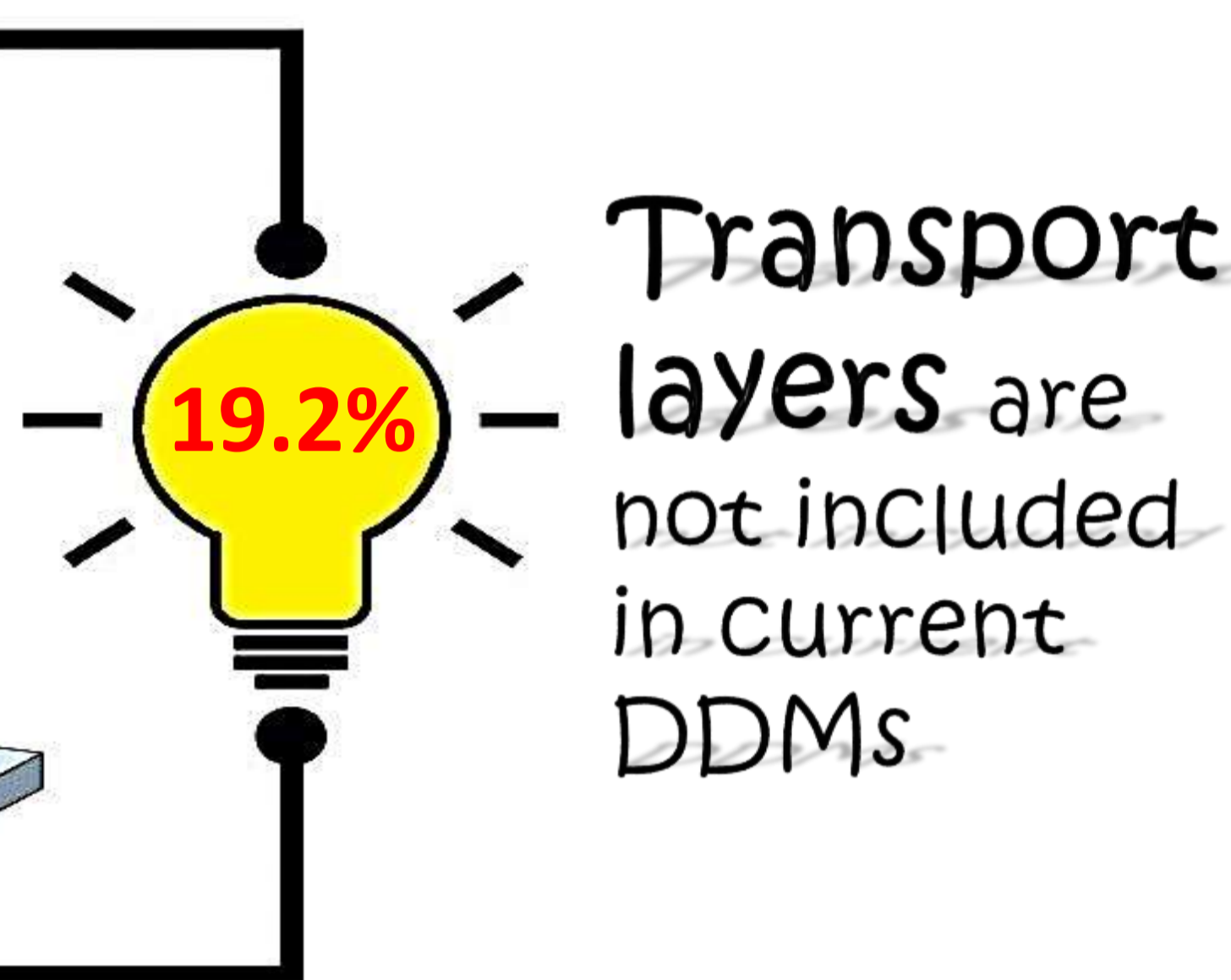
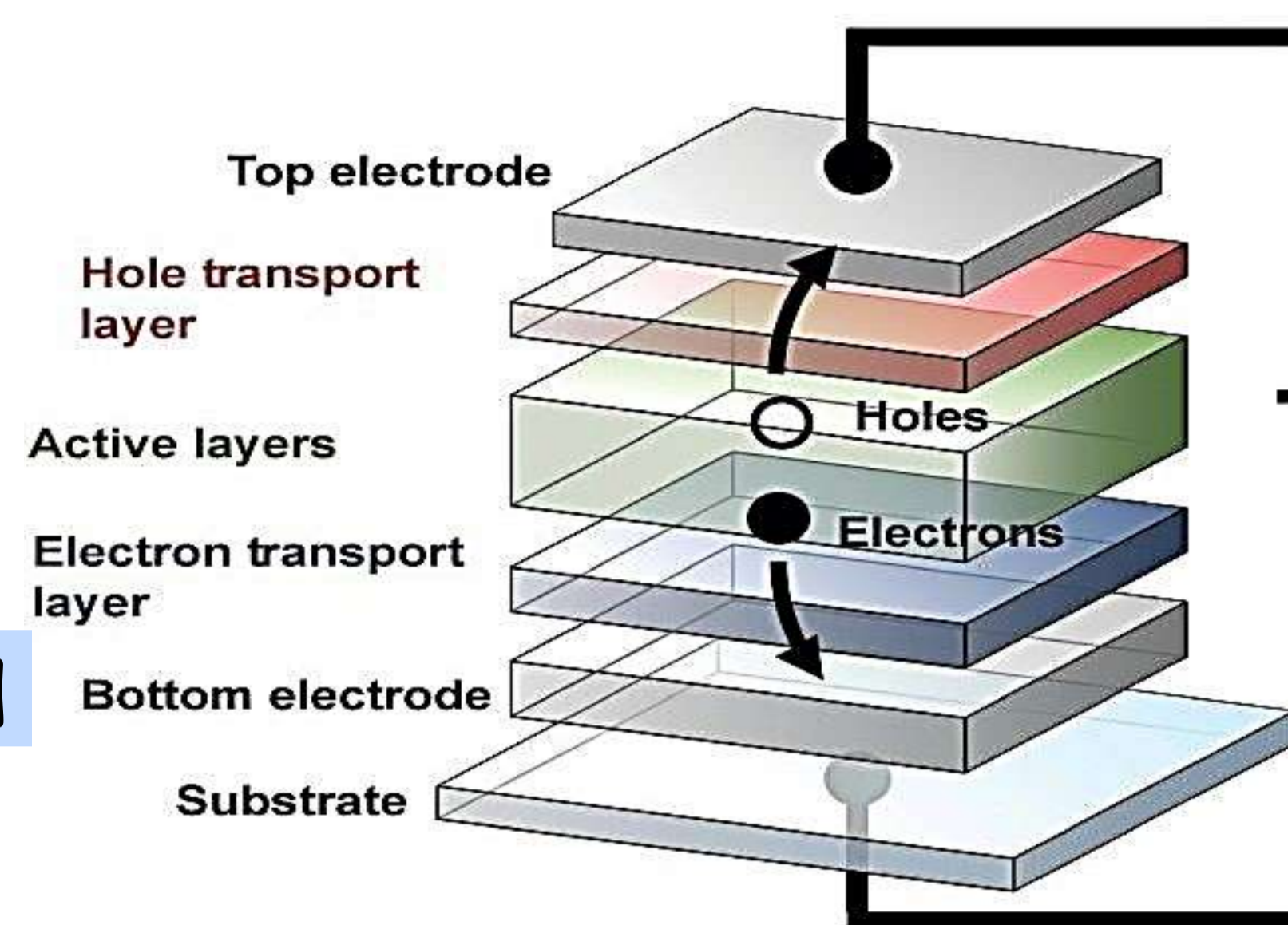
Motivation



Theoretical explanations needed!

Comprehensive drift-diffusion model (DDM) should be developed

- low-cost,
- lightweight,
- flexible,
- ideal for roll-to-roll large-scale processing...



Transport layers are not included in current DDMs

Drift-diffusion model

- ϕ - electrostatic potential
- q - elementary charge,
- n and p - electrons and holes densities
- D_n and D_p - electron and hole diffusion coefficients
- G is generation term described by Beer-Lambert law

Continuity equations:

$$-n(x) \cdot \mu_n \cdot \frac{\partial^2 \phi(x)}{\partial x^2} - \mu_n \cdot \frac{\partial \phi(x)}{\partial x} \cdot \frac{\partial n(x)}{\partial x} + D_n \cdot \frac{\partial^2 n(x)}{\partial x^2} = R - G$$

$$-p(x) \cdot \mu_p \cdot \frac{\partial^2 \phi(x)}{\partial x^2} - \mu_p \cdot \frac{\partial \phi(x)}{\partial x} \cdot \frac{\partial p(x)}{\partial x} - D_p \cdot \frac{\partial^2 p(x)}{\partial x^2} = G - R$$

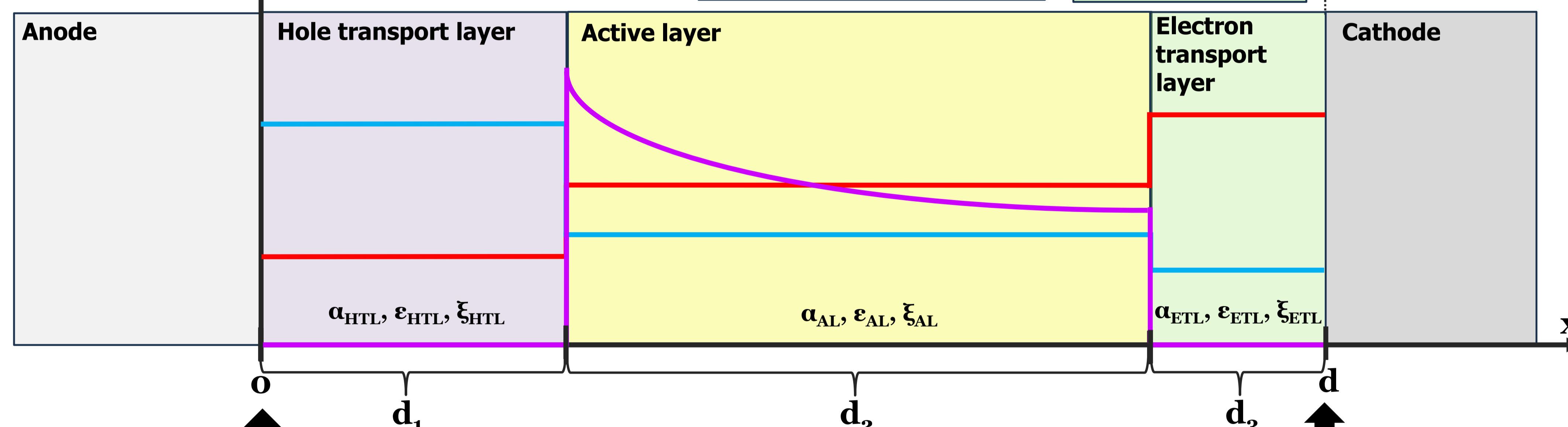
Poisson's equation:

$$\frac{\partial^2 \phi(x)}{\partial x^2} = \frac{q}{\epsilon} (n(x) - p(x))$$

- ϵ - permittivity
- μ_n and μ_p - electron and hole mobilities
- α - absorption coefficient

- $R = \xi \frac{q \mu_n + \mu_p}{\epsilon} \cdot$ reduced Langevin recombination rate
- ξ - reduction factor

The system of equations was solved with use of the finite difference discretization improved by Scharfetter and Gummel approach and the Newton algorithm.



Boundary condition:

$$\phi(x=0) = 0$$

$$n(x=0) = n_{th}^a = N_c \exp[-(E_g - \Phi_p)/k_B T]$$

$$p(x=0) = p_{th}^a = N_v \exp[-\Phi_p/k_B T]$$

- Φ_n and Φ_p - injection barrier heights of holes and electrons respectively
- n_{th}^a and n_{th}^c - thermionic charge carrier densities of electrons at anode and cathode respectively
- p_{th}^a and p_{th}^c - thermionic charge carrier densities of holes at anode and cathode respectively
- N_c and N_v - effective density of states
- E_g - energy gap

Boundary condition:

$$\phi(x=d) = V + V_{bi}$$

$$n(x=d) = n_{th}^c = N_c \exp[-\Phi_n/k_B T]$$

$$p(x=d) = p_{th}^c = N_v \exp[-(E_g - \Phi_n)/k_B T]$$

Conclusions

- A simple way of including transport layers in the DDM is presented – each layer (HTL, AL and ETL) is described with its electrical and optical parameters. Hole and electron injection barriers are considered.
- **Model validation 1.** J-V curve simulations show expected trends with changing hole/electron injection barriers.
- **Model validation 2.** Simulated J-V curves of ITO/P3HT:PCBM/Al device (structure without transport layers) reproduce the experiment well when realistic values of hole/electron injection barriers are applied in the DDM.
- **Model validation 3.** Simulated J-V curves of ITO/PEDOT:PSS/P3HT:PCBM/LiF/Al (structure with transport layers) show excellent agreement with experiment when zero hole/electron injection barriers are used in the DDM – this confirms electrodes Fermi level pinning.

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Results

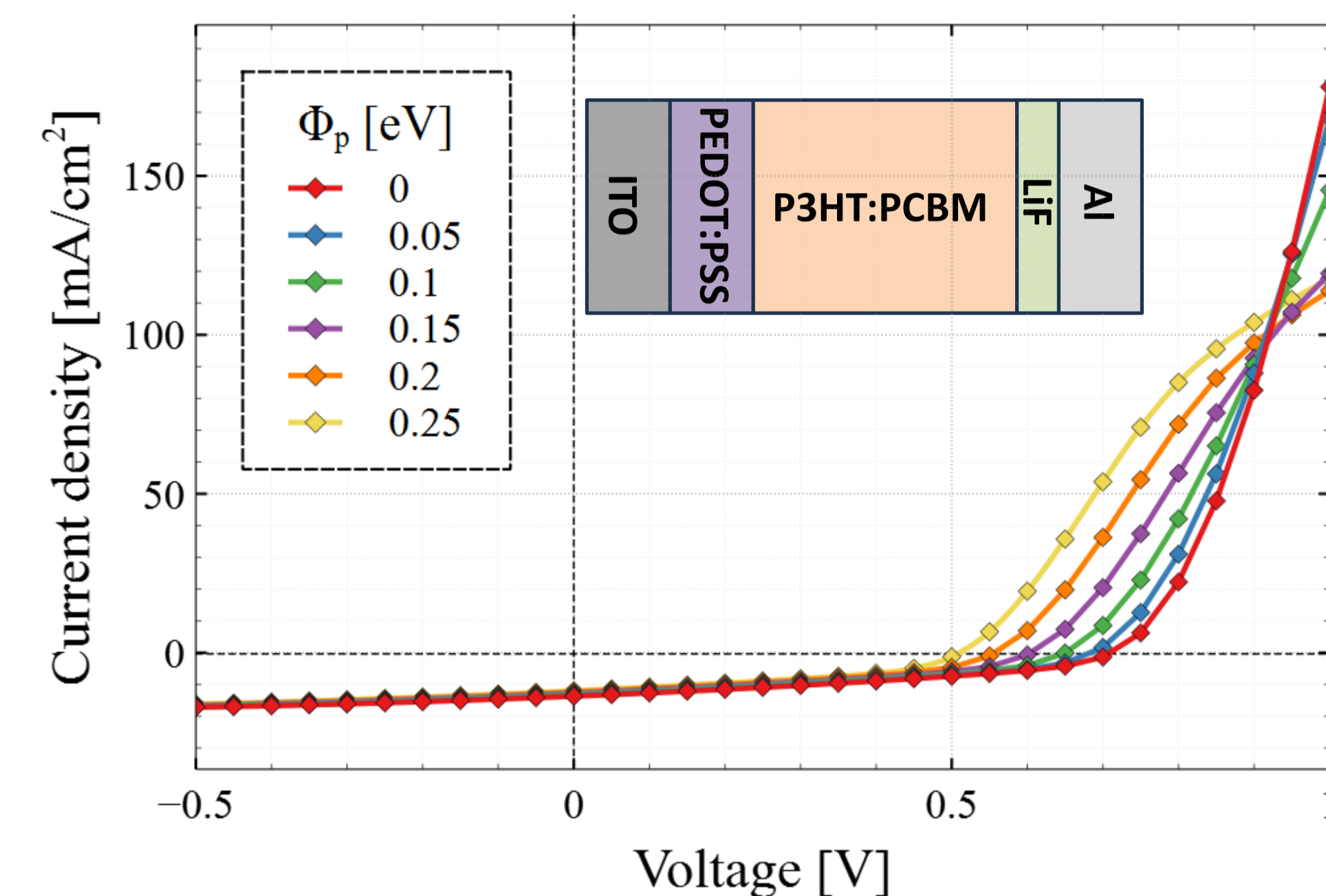


Fig. 1. J-V curves simulated for different hole injection barriers using DDM with included transport layers.

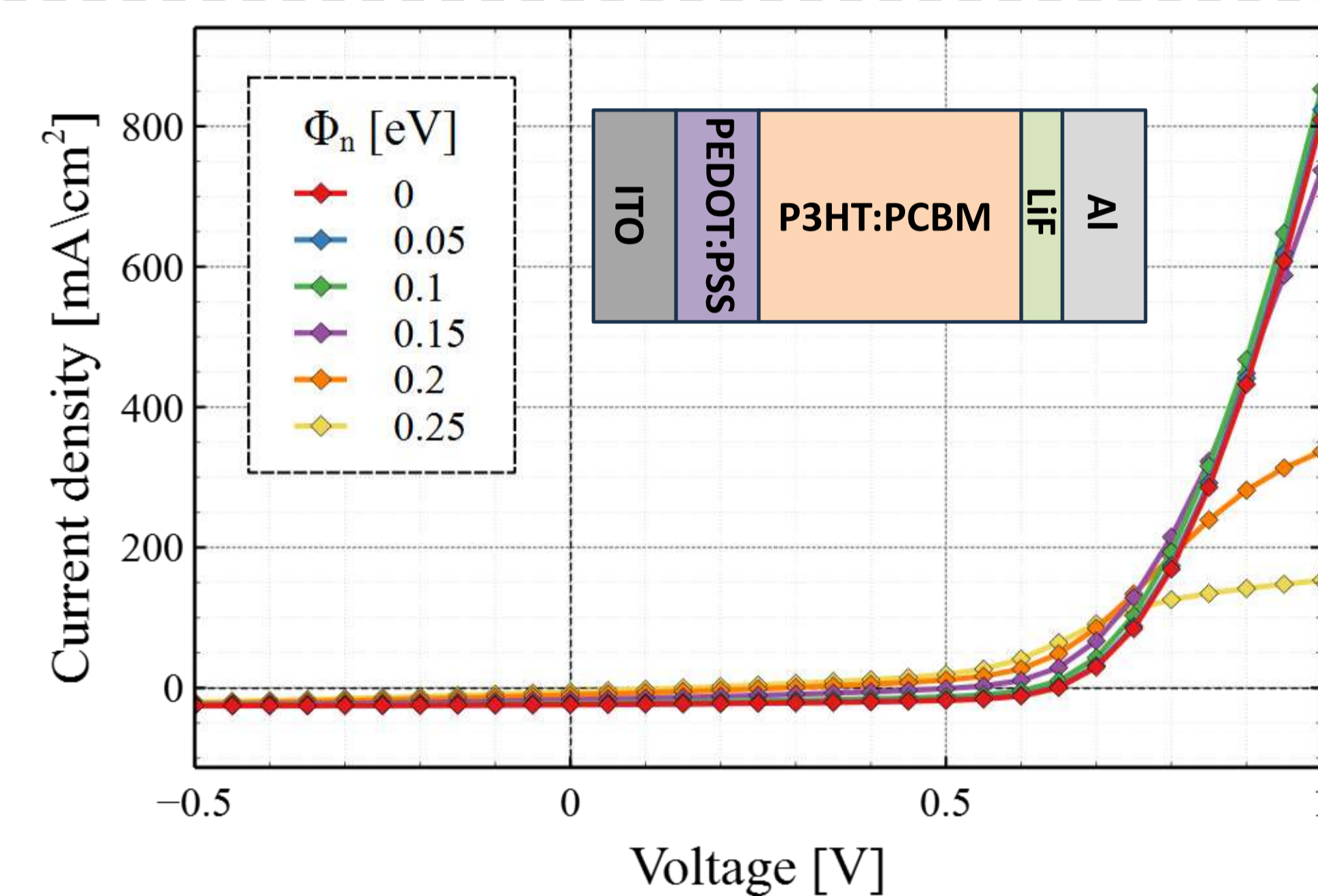


Fig. 2. J-V curves simulated for different electron injection barriers using DDM with included transport layers.

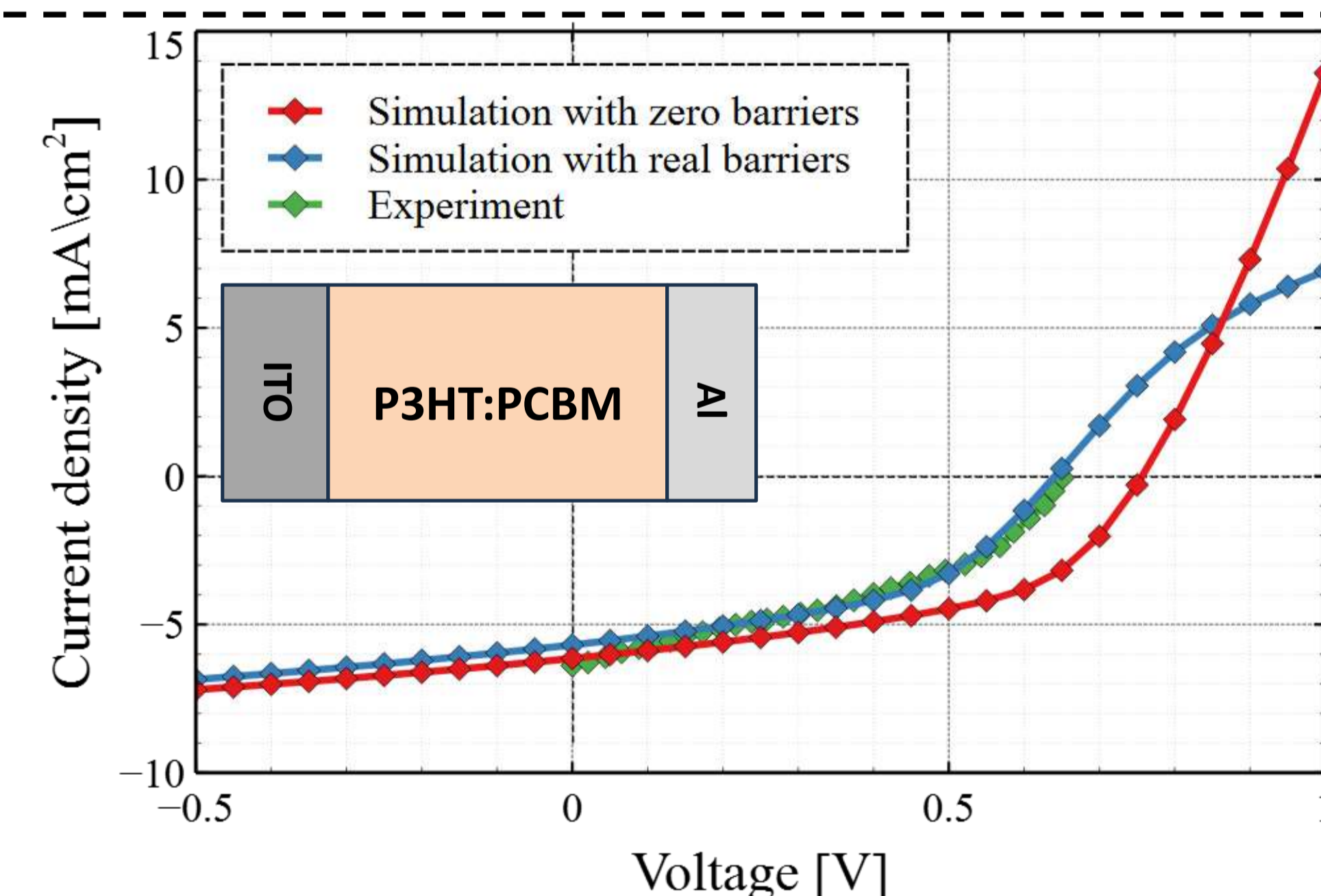


Fig. 3. Simulated J-V curves for the structure without transport layers using zero and realistic injection barrier values in the DDM compared to the measured J-V curve.

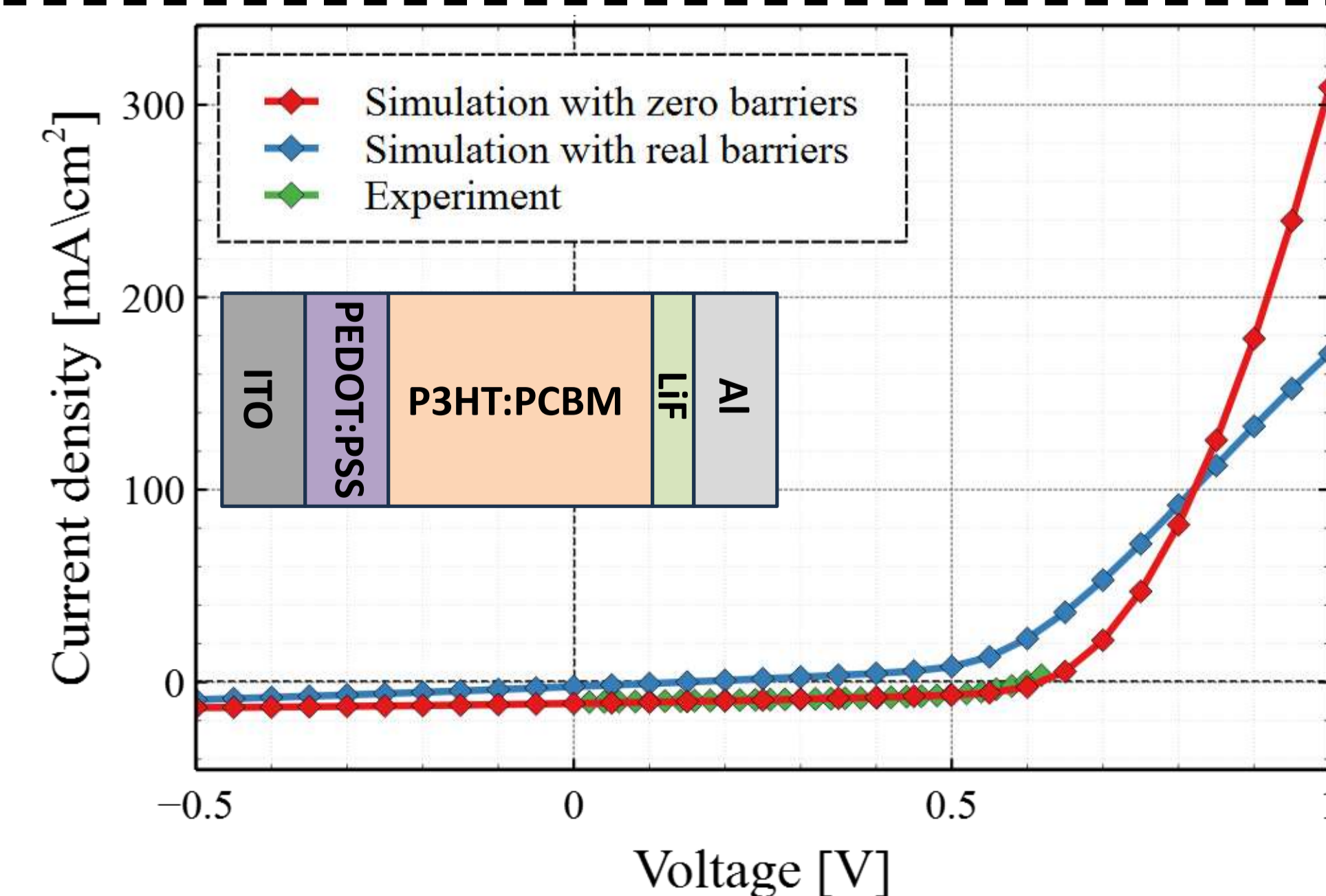


Fig. 4. Simulated J-V curves for the structure with transport layers using zero and realistic injection barrier values in the DDM compared to the measured J-V curve.